

Mechanisms of Decrease in Hole Concentration in Al-doped 4H-SiC by Irradiation of 200 keV Electrons

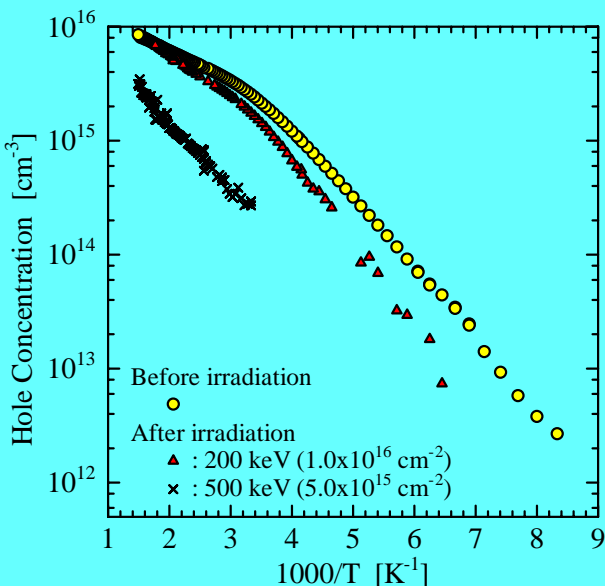
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Abstract. From the temperature dependence of the hole concentration $p(T)$ in lightly Al-doped 4H-SiC epilayer irradiated with several fluences of 200 keV electrons, the density (N_{Al}) of Al acceptors with $E_V+0.2$ eV decreases significantly with increasing fluence, whereas the density (N_{Defect}) of unknown acceptors (or defects) with $E_V+0.37$ eV increases with fluence at first and then decreases slightly. Although only C vacancies increases with fluence because 200 keV electrons can displace only C atoms, only the increase in the density of C monovacancies (V_C) located at midgap cannot explain the changes of $p(T)$ by 200 keV electron irradiation. In order to explain the fluence dependences of N_{Al} and N_{Defect} , it may be necessary to consider the relationship between C vacancies and Al acceptors.

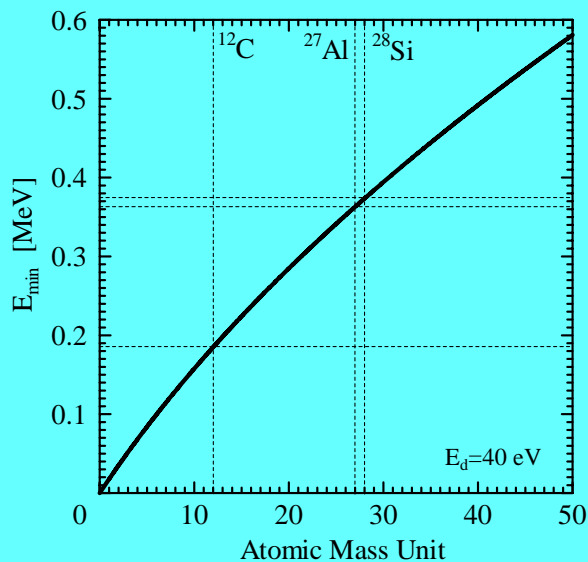
Introduction

Irradiation-energy dependence of $p(T)$
(Refs. 1,2)



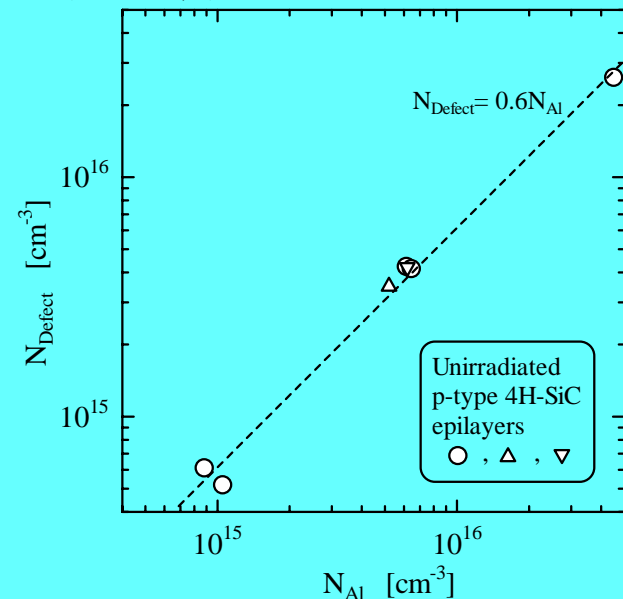
Although the fluence of 200 keV electrons is higher, the $p(T)$ decreases less than due to 500 keV electron irradiation.

Atomic-mass-unit dependence of minimum electron energy required for displacement of substitutional atom in SiC (Ref. 1)



Energy	Displaced atoms
200 keV	→ only C atoms
500 keV	→ C, Al and Si atoms

Relationship between N_{Al} and N_{Defect}
(Refs. 1,3)



$$N_{Defect} = 0.6 \times N_{Al}$$

Unknown acceptors with $E_V+0.37$ eV are related to Al.

References

- 1) Hideharu Matsuura, et al.: “Relationship between defects induced by irradiation and reduction of hole concentration in Al-doped 4H-SiC”, *Physica B* 376-377 (2006) 342-345.
- 2) Hideharu Matsuura, et al.: “Decrease in Al acceptor density in Al-doped 4H-SiC by irradiation with 4.6 electrons”, *Appl. Phys. Lett.* 83 (2003) 4981-4983.
- 3) Hideharu Matsuura, et al.: “Dependence of acceptor levels and hole mobility on acceptor density and temperature in Al-doped p-type 4H-SiC epilayers”, *J. Appl. Phys.* 96 (2004) 2708-2715.